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| <b>PTO-1449</b><br><br><b>Information Disclosure Citation<br/>In an Application</b> | Application No.<br><b>10/623757</b>        | Applicant(s)<br><b>Jin (nmi) Zhao, et al.</b> |                                     |
|   | Docket Number<br>TI-35855<br>(032350.B505) | Group Art Unit<br><b>Unknown</b>              | Filing Date<br><b>July 21, 2003</b> |

### U.S. PATENT DOCUMENTS

|  |   | DOCUMENT NO. | DATE | NAME | CLASS | SUBCLASS | FILING DATE |
|--|---|--------------|------|------|-------|----------|-------------|
|  | A |              |      |      |       |          |             |
|  | B |              |      |      |       |          |             |
|  | C |              |      |      |       |          |             |
|  | D |              |      |      |       |          |             |
|  | E |              |      |      |       |          |             |
|  | F |              |      |      |       |          |             |
|  | G |              |      |      |       |          |             |
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### FOREIGN PATENT DOCUMENTS

|  |   | DOCUMENT NO. | DATE | COUNTRY | CLASS | SUBCLASS | TRANSLATION |    |
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|  | K |              |      |         |       |          |             |    |
|  | L |              |      |         |       |          |             |    |
|  | M |              |      |         |       |          |             |    |
|  | N |              |      |         |       |          |             |    |

|        |   | DOCUMENT (Including Author, Title, Source, and Pertinent Pages)  | DATE          |
|--------|---|--|---------------|
| /F.S./ | O | G. Bruno, et al., " <i>Study of the NF<sub>3</sub> plasma cleaning of reactors for amorphous silicon deposition</i> ," © 1994 American Vacuum Society, J. Vac. Sci. Technol. A 12(3), pages 690-698.                               | May/June 1994 |
| /F.S./ | P | Srihari Ponnekanti, et al., " <i>Failure mechanisms of anodized aluminum parts used in chemical vapor deposition chambers</i> ," © 1996 American Vacuum Society, J. Vac. Sci. Technol. A 14(3), pages 1127-1131.                   | May/June 1996 |
| /F.S./ | Q | Hsin-Pai Hsueh, et al., " <i>Ion energy distributions and optical emission spectra in NF<sub>3</sub>-based process chamber cleaning plasmas</i> ," © 2001 American Vacuum Society, J. Vac. Sci. Technol. B 19(4), pages 1346-1357. | Jul/Aug 2001  |
|        | R |  |               |

EXAMINER

/Francis Smith/

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